

INDIAN INSTITUTE OF TECHNOLOGY MADRAS Chennai 600 036

Telephone: [044] 2257 9763 E-mail: tender@imail.iitm.ac.in



The Senior Manager (Project Purchase)

Open Tender Reference No: ME/MSRO/147/2023/SPUTTERCOATR

GEM NAR ID: GEM/GARPTS/27072023/G5QUXA2A3W55

Dear Sir/Madam,

On behalf of the Indian Institute of Technology Madras, Tenders are invited in two bid system from Class-I local suppliers and Class II local suppliers, for the supply of: "**Table Top Sputter Coater**" Conforming to the specifications given in **Annexure -A**.

Tender Documents may be downloaded from Central Public Procurement Portal <u>https://etenders.gov.in/eprocure/app</u>. Aspiring Bidders who have not enrolled / registered in e-procurement should enroll / register before participating through the website <u>https://etenders.gov.in/eprocure/app</u>. The portal enrolment is free of cost. Bidders are advised to go through instructions provided at "**Help for vendors**". [Special Instructions to the Vendors/Bidders for the e-submission of the bids online through this eProcurement Portal"]

Bidders can access tender documents on the website (For searching in the NIC site, kindly go to Tender Search option and type 'IIT'. Thereafter, click on "GO" button to view all IIT Madras tenders). Select the appropriate tender and fill them with all relevant information and submit the completed tender document online on the website <u>https://etenders.gov.in/eprocure/app</u> as per the schedule attached.

<u>1)</u>	Pre-bid Meeting Details	•	NA
<u>2)</u>	ICSR Vendor Registration	••	<u>Vendor registration code</u> . Vendor registration with IC&SR (IITM) is mandatory for bidders to participate in tenders. ** <u>For Vendor Registration & Guidelines, Please follow the website</u> : <u>https://icandsr.iitm.ac.in/vendorportal</u> ; Helpdesk: <u>vendorhelpdesk@icsrpis.iitm.ac.in</u>

<u>No manual bids will be accepted.</u> All tender documents including Technical and Financial bids should be submitted in the E-procurement portal.

Last date for receipt of tender		22.08.2023 @ 3:00 PM
Date & time of opening of tender	••	23.08.2023 @ 3:00 PM

Date: 02.08.2023

Due Date/Time: 22.08.2023@ 3:00 PM

<u>3. Instructions to the Bidder:</u>

<u>A)</u>	Searching for tender documents	:	 There are various search options built in the CPP Portal, to facilitate bidders to search active tenders by several parameters. These parameters could include Tender ID, organization name, location, date, value, etc. There is also an option of advanced search for tenders, wherein the bidders may combine a number of search parameters such as organization name, form of contract, location, date, other keywords etc. to search for a tender published on the CPP Portal. Once the bidders have selected the tenders they are interested in, they may download the required documents / tender schedules. These tenders can be moved to the respective "My Tender" folder. This would enable the CPP Portal to intimate the bidders through SMS / email in case there is any corrigendum issued to the tender document. The bidder should make a note of the unique Tender ID assigned to each tender, in case they want to obtain any clarification / help
B)	Assistance to bidders		from the Helpdesk.
<u>B)</u>	Assistance to bluders	•	 Any queries relating to the tender document and the terms and conditions contained therein should be addressed to the Tender Inviting Authority for a tender or the relevant contact person indicated in the tender. Any queries relating to the process of online bid submission or queries relating to CPP Portal in general may be directed to the 24x7 CPP Portal Helpdesk. The contact number for the helpdesk is [0120-4200462, 0120-4001002, 0120-4001005]
<u>C)</u>	Enrollment Process to Bidders	:	REGISTRATION
			 Bidders are required to enroll on the e-Procurement module of the Central Public Procurement Portal URL:https://etenders.gov.in/eprocure/app by clicking on "Online Bidder Enrollment". Enrollment on the CPP Portal is free of charge. As part of the enrolment process, the bidders will be required to choose a unique username and assign a password for their accounts. Bidders are advised to register their valid email address and mobile numbers as part of the registration process. These would be used for any communication from the CPP Portal. Upon enrolment, the bidders will be required to register their valid Digital Signature Certificate (Class II or Class III Certificates with signing key usage) issued by any Certifying Authority recognized by CCA India (e.g. Sify / TCS / nCode / eMudhra etc.) Only one valid DSC should be registered by a bidder. Please note that the bidders are responsible to ensure that they do not lend their DSCs to others which may lead to misuse. Bidder then may log in to the site through the secured log-in by entering their user ID / password and the password of the DSC / eToken. Possession of a Valid Class II/III Digital Signature Certificate (DSC) in the form of smart card/e-token in the company's name is a prerequisite for registration and participating in the bid

			submissionactivitiesthroughhttps://etenders.gov.in/eprocure/app• Digital Signature Certificates can be obtained from the
			authorized certifying agencies, details of which are available in the web site https://etenders.gov.in/eprocure/app under the "Information about DSC".
<u>D)</u>	Preparation of bids	•	Bidder should take into account any corrigendum published on the tender document before submitting their bids.
		•	Please go through the tender advertisement and the tender document carefully to understand the documents required to be submitted as part of the bid. Please note the number of covers in which the bid documents have to be submitted, the number of documents including the names and content of each of the document that need to be submitted. Any deviations from these may lead to rejection of the bid.
		•	Bidder, in advance, should prepare the bid documents to be submitted as indicated in the tender document / schedule and generally shall be in PDF / XLS formats as the case may be. Bid documents may be scanned with 100 dpi with black and white option.
		•	To avoid the time and effort required in uploading the same set of standard documents which are required to be submitted as a part of every bid, a provision of uploading such standard documents (e.g. PAN card copy, GSTIN Details, annual reports, auditor certificates etc.) has been provided to the bidders. Bidders can use "My Documents " area available to them to upload such documents. These documents may be directly submitted from the "My Documents " area while submitting a bid, and need not be uploaded again and again. This will lead to a reduction in the time required for bid submission process.
<u>E)</u>	Submission of bids	•	Bidder should log into the site well in advance for bid submission so that he/she can upload the bid in time i.e. on or before the bid submission date and time. Bidder will be responsible for any delay due to other issues.
		•	The bidder has to digitally sign and upload the required bid documents one by one as indicated in the tender document.
		•	Bidder has to select the bid security declaration. Otherwise, the tender will be summarily rejected.
		•	A standard BOQ format has been provided with the tender document to be filled by all the bidders. Bidders are requested to note that they should necessarily submit their financial bids in the format provided and no other format is acceptable. Bidders are required to download the BOQ file, open it and complete the detail with their respective financial quotes and other details (such as name of the bidder). If the BOQ file is found to be modified by the bidder, the bid will be rejected.
		•	The server time (which is displayed on the bidders' dashboard) will be considered as the standard time for referencing the deadlines for submission of the bids by the bidders, opening of bids etc. The bidders should follow this time during bid submission.
		•	The Tender Inviting Authority (TIA) will not be held responsible for any sort of delay or the difficulties faced during the submission

		of bids online by the bidders due to local issues.
		 The uploaded tender documents become readable only after the tender opening by the authorized bid openers.
		• Upon the successful and timely submission of bids, the portal will give a successful bid submission message & a bid summary will be displayed with the bid no. and the date & time of submission of the bid with all other relevant details.
		 Kindly add scanned PDF of all relevant documents in a single PDF file of compliance sheet. More information useful for submitting online bids on the CPP Portal may be obtained at: <u>https://etenders.gov.in/eprocure/app</u>. All tender documents including pre-qualification bid, Technical Bid &Financial Bid should be submitted separately in online CPP portal as per the specified format only. Right is reserved to ignore any tender which fails to comply with the above instructions. No manual bid submission will be entertained.
<u>F)</u>	Marking on Technical Bid	• The bidder eligibility criteria, technical specification and supply of item for this tender is given in Annexure A.
		• The Bidders shall go through the specification and submit the technical bid.
		• The Technical bid should be submitted in the proforma as per Annexure-B in pdf format only through online (e-tender). No manual submission of bid will be entertained.
		• The technical bid should have a page-wise heading as "Technical Bid" and page no. in all pages with seal and signature of authorized signatory. The total no. of pages should be mentioned at the last page of the documents.
		• The technical bid should consist of bidder eligibility criteria details and all technical details along with catalogue/ pamphlet which will give a detailed description of product with technical data sheet so that technical compliance can be verified.
<u>G</u>)	Marking on Price Bid	• Financial bid (BoQ) should be submitted in the prescribed proforma format as per Annexure-C in xls format through e-tender only. No manual or other form of submission of Financial Bid will not be entertained

4)	Preparation of Tender: The bidders should submit the bids in two bid system as detailed below.
	Bid I _Technical Bid
	The technical bid should consist of bidder eligibility criteria and technical specification compliance sheet as per Annexure-B.
	Bid II _Price Bid
	The price bid should be submitted in excel format (BoQ) as per the proforma (Annexure C) uploaded in the e-Tender web site. The Quoted price should be for supply and installation of the item and inclusive of all cost and statutory levies at IIT Madras.
5)	Price:
	a) The price should be quoted only in INR net per unit (after breakup) and must include all packing, transit insurance and delivery charges to the Department of Physics.
	b) The rate quoted shall be all inclusive of all taxes and no extra payment will be made other than statutory revisions as per the terms and conditions stipulated in this contract document.
	c) The percentage of tax & duties should be clearly indicated separately. IIT Madras is eligible for custom duty (5.5%). Relevant certificates will be issued wherever necessary.
	d) The offer/bids should be submitted through online only in two bid system i.e. Technical Bid and Financial Bid separately.
6)	Tenderer shall submit along with this tender:
	(i) Proof of having ISO or other equivalent certification given by appropriate authorities.
	(ii) Name and full address of the Banker and their swift code and PAN No. and GSTIN number.
	(iii) GST registration proof showing registration number, area of registration etc.
	 (iv) All of your future correspondences including Invoices should bear the GST No. and Area Code.
7)	Terms of Delivery:
	Supplier will be fully responsible for the safe carriage, Installation/Commissioning of goods up to the Department of Physics., or named place as per PO, Insurance coverage will be in the scope of the supplier.
	The tenderer should indicate clearly the time required for delivery of the item (subject to the approval of the Executive Committee-IIT-Madras). In case there is any deviation in the delivery schedule, liquidated damages clause will be enforced or penalty for the delayed supply period will be levied.
	In the event of delay or non-supply of materials/execution of Contract beyond the date of delivery/completion of job. The penalty will be levied @1% per week of delay subject to a max of 10% of the value of purchase order and if the delay is more than accepted time frame by IIT M, the PO would be partially or fully cancelled and liquidated damages will be enforced accordingly.
8)	Period for which the offer will remain open:
	The Tender shall remain open for acceptance/validity till: 180 days from the date of opening of the tender. However, the day up to which the offer is to remain open being declared closed holiday for the Indian Institute of Technology Madras, the offer shall remain open for acceptance till the next working day.
9) a,	EMD : The EMD of Rs.1,20,000 to be transferred to the account details mentioned in Annexure G and proof should be enclosed in the Technical Bid. Any offer not accompanied with the EMD shall be rejected summarily as non-responsive.
	The EMD of the unsuccessful bidders shall be returned within 30 days of the end of the bid validity period. The same shall be forfeited, if the tenderers withdraw their offer after the opening during the bid $\frac{5}{5}$

	validity period. The Institute shall not be liable for payment of any interest on EMD. EMD is exempted
	for Micro and Small Enterprises (MSE) as defined in MSE Procurement Policy issued by Department of Micro, Small and Medium Enterprises (MSME) and Startups as recognized by Department of Industrial Policy & Promotion (DIPP). (MSE/MSME/DIPP PROOF should be enclosed in the cover containing technical bid)
b,	Performance Security : The successful bidder should submit Performance Security for an amount of 5% of the basic invoice value of the contract/supply. The Performance Security may be furnished in the form of an Account Payee DD,FD Receipt in the name of "The Registrar, IIT Madras" from any scheduled commercial bank or Bank Guarantee from any scheduled commercial bank in India. The performance security should be furnished within 14 days from the date of the purchase order. Performance Security in the form of Bank Guarantee: - In case the successful bidder wishes to submit Performance Security in the form of Bank Guarantee, the Bank Guarantee should be routed directly to IIT Madras from the Bank. The Bank Guarantee should remain valid for a period of sixty days beyond the date of completion of all
10)	contractual obligations of the supplier including the warranty obligations.For the same tender, either the OEM or the authorized dealer/service provider can only quote. But both of them cannot quote separately for the same tender.
11)	The offers/bids should be sent only for a item/Equipments of latest version that is available in the market and supplied to a number of customers. A list of customers in India with details must accompany the quotations. Quotations for a prototype machine will not be accepted
12)	Original catalogue (not any photocopy) of the quoted model duly signed by the principals must accompany the quotation in the Technical bid.
13)	Compliance or Confirmation report with reference to the specifications and other terms & conditions should also be obtained from the principal/OEM.
14)	Risk Purchase Clause
	In the event of failure of supply of the item/equipment within the stipulated delivery schedule, the purchaser has all the right to purchase the item/equipment from other sources on the total risk of the supplier under risk purchase clause.
15)	Payment:
	(i) No Advance payment will be made. However, 90% Payment against Delivery and 10% after installation are agreed to wherever the installation is involved.
	(ii) Advance Payment: No advance payment is generally admissible. In case a specific percentage of advance payment is required, the Vendor has to submit a Bank Guarantee from a scheduled commercial bank in India equivalent to the amount of advance payment.
16)	On-site Installation:
	The equipment/item or Machinery has to be installed or commissioned by the successful bidder within the number of days (as prescribed by PI) from the date of receipt of the item at the site of IIT Madras.
17)	Warranty/Guarantee:
	The offer should clearly specify the warranty or guarantee period for the machinery/equipment. Any extended warranty offered for the same has to be mentioned separately (For more details please refer our Technical Specifications).
	** Note: PO which involves installation, warranty/guarantee shall be applicable from date of installation.
18)	Acceptance and Rejection:
	Failure to comply with any of the instructions stated in this document or offering unsatisfactory explanations for non-compliance will likely to lead to rejection of offers.
	I.I.T. Madras has the right to accept the whole or any part of the Tender or portion of the

	quantity offered or rejects it in full without assigning any reason.
19)	Debarment from Bidding:
	In case of breach of Terms & Conditions, Bidder may be suspended from being eligible for bidding in any contract with the IIT Madras up to 2 Years [as per Rule 151(iii) of GFR] from the date of Tender.
20)	Disputes and Jurisdiction:
	 Settlement of Disputes: Any dispute, controversy or claim arising out of or in connection with this PO including any question regarding its existence, validity, breach or termination, shall in the first instance be attempted to be resolved amicably by both the Parties. If attempts for such amicable resolution fails or no decision is reached within 30 days whichever is earlier, then such disputes shall be settled by arbitration in accordance with the Arbitration and Conciliation Act, 1996. Unless the Parties agree on a sole arbitrator, within 30 days from the receipt of a written request by one Party from the other Party to so agree, the arbitral panel shall comprise of three arbitrators. In that event, the supplier will nominate one arbitrator and the Project Coordinator of IITM shall nominate on arbitrator. The Dean IC&SR will nominate the Presiding Arbitrator of the arbitral tribunal. The arbitration proceeding shall be carried out in English language. The cost of arbitration and fees of the arbitrator(s) shall be shared equally by the Parties. The seat of arbitration shall be at IC&SR IIT Madras, Chennai. a. The Applicable Law: The Purchase Order shall be construed, interpreted and governed by the Laws of India. Court at Chennai shall have exclusive jurisdiction subject to the arbitration clause.
	 Any legal disputes arising out of any breach of contact pertaining to this tender shall be settled in the court of competent jurisdiction located within the city of Chennai in Tamil Nadu.
21)	Force Majeure: The Supplier shall not be liable for forfeiture of its performance security, liquidated damages or termination for default, if and to the extent that, it's delay in performance or other failure to perform its obligations under the Contract is the result of an event of Force Majeure.
	For purposes of this Clause, "Force Majeure" means an event beyond the control of the Supplier and not involving the Supplier's fault or negligence and not foreseeable. Such events may include, but are not limited to, acts of the Purchaser either in its sovereign or contractual capacity, wars or revolutions, fires, floods, epidemics, quarantine restrictions and freight embargoes.
	If a Force Majeure situation arises, the Supplier shall promptly notify the Purchaser in writing of such conditions and the cause thereof. Unless otherwise directed by the Purchaser in writing, the Supplier shall continue to perform its obligations under the Contract as far as is reasonably practical, and shall seek all reasonable alternative means for performance not prevented by the Force Majeure event.
22)	Eligibility Criteria:
	As per the Government of India Order, only "Class - I Local Suppliers" and "Class - II Local Suppliers" <u>can participate in this tender.</u>
	Bidder should confirm their acceptance that they comply with the provisions with report to "Guidelines for eligibility of a bidder from a country which shares a land border with India as detailed at Annexure-E. The bidder should submit Certificate for "Bidder from/ Not from Country sharing Land border with India & Registration of Bidder with Competent Authority" as per Order of DoE F.No.6/18/2019-PPD dated 23.07.2020 as mentioned.
23)	Preference to "class I Local Suppliers" : preference will be given to " class 1 local suppliers " (subject to class -I local supplier's quoted price falling within the margin of purchase preference) as per public procurement (preference to make in India) order 2017 .O.M No P- 45021/2/2017 – pp(BE - 11) dt 04/06/2020 subject to the conditions that the "class 1 Local Supplier" should agree to supply goods / provide service at L1 rate and furnish a certificate with the technical bid document that the goods/service provided by them consists local content equal to or more than 50%.(certificate from Chartered Accountant in case value of contract exceeds Rs 10 crore).

	Class - I local supplier' means a supplier or service provider whose goods, services or works offered for procurement consists of local content equal to or more than 50% as defined under the
	above said order. Declaration to be provided as per Annexure-D per item/service/work.
	➤ 'Class - II local supplier' means a supplier or service provider whose goods, services or works
	offered for procurement consists of local content equal to 20% but less than 50% as defined under
	the above said order. Declaration to be provided as per Annexure-D per item/service/work.
	> 'Margin of purchase preference': - The margin of purchase preference shall be 20%. The
	Definition of the margin of purchase preference is defined in the Govt. of India Order No: P-
	45021/12/2017-PP (BE-II) Dt.4th June, 2020) Order 2017. As per the Government of India
	Order – "Margin of Purchase Preference" means the maximum extent to which the price
	quoted by a "Class-I local supplier" may be above the L1 for the purpose of purchase
	preference.
	**Note: Local content percentage to be calculated in accordance with the definition provided at
	clause 2 of revised public procurement preference to Make in India Policy vide GoI Order no. P-
	45021/2/2017-PP (B.EII) dated 15.06.2017 (subsequently revised vide orders dated 28.05.2018,
	29.05.2019and 04.06.2020) MOCI order No. 45021/2/2017-PP (BE II) Dt.16th September 2020 & P-
	45021/102/2019-BE-II-Part(1) (E-50310) Dt.4th March 2021
24)	Evaluation of Bids
24)	Bid evaluation will take place in two stages.
	Stage I Technical Bid evaluation
	All bidders who have fully complied with bidder eligibility criteria I,II and technical evaluation
	(Annexure A) will only be considered for opening of price bid.
	Stage II: Price Bid Evaluation
	The price bid evaluation will be based on price quoted by the bidder. The rate quoted for Table
	Top Sputter Coater will alone be taken up for arrival of Lowest Bid (L1) value.
25)	Selection of successful bidder and Award of Order
2 0)	The order will be directly awarded to the technically qualified bidder as per the condition in para 3A of
	DIPP, MoCI Order No. 45021/2/2017-PP (BE II) dated 16th September 2020.
26)	All information including selection and rejection of technical or financial bids of the prospective bidders
20)	will be communicated through e-Tender portal. In terms of Rule 173(iv) of General Financial Rule 2017,
	the bidder shall be at liberty to question the bidding conditions, bidding process and/or rejection of bids.
27)	The tenderer shall certify that the tender document submitted by him / her are of the same replica of the
	tender document as published by IIT Madras and no corrections, additions and alterations made to the
	same. If any deviation found in the same at any stage and date, the bid / contract will be rejected /
	terminated and actions will be initiated as per the terms and conditions of the contract.
28)	Due to Covid-19 pandemic pre-bid meeting will be conducted through online. Clarification to the queries
20)	and doubts raised by the bidders will be issued as a corrigendum/addendum in the e-tenders portal.
20)	Due to Covid-19 pandemic the bidders will not be entertained to participate in opening of Bids. Since the
29)	tender is e-tender, the opening of the bids may be checked using the respective logins of the bidders.

ACKNOWLEDGEMENT

It is hereby acknowledged that I/We have gone through all the points listed under "Specification, Guidelines, Terms and Conditions" of tender document. I/We totally understand the terms and conditions and agree to abide by the same.

SIGNATURE OF TENDERER ALONG WITH SEAL OF THE COMPANY WITH DATE

Bidder Eligibility Criteria and Technical Specification for Table Top Sputter Coater Tender No. ME/MSRO/147/2023/SPUTTERCOATR

Bidder Eligibility Criteria – I (Public Procurement – Preference to Make in India)

1. Only 'Class-I local suppliers' and 'Class-II local suppliers', as defined under DIPP, MoCI Order No. P-45021/2/2017-PP (BE-II) dated 16th September 2020 and other subsequent orders issued therein.

2. EMD as per Tender or EMD is exempted for Micro and Small Enterprises (MSE) as defined in MSE Procurement Policy issued by Department of Micro, Small and Medium Enterprises (MSME) and Startups as recognized by Department of Industrial Policy & Promotion (DIPP). (MSE/MSME/DIPP PROOF should be enclosed in the cover containing technical bid).

Bidder Eligibility Criteria – II

1. The participating Bidder's firm shall be the Original Equipment Manufacturer (OEM) or OEM Certified / authorized firm. (Annexure F)

2. The bidder/OEM should have supplied at least 5 similar system or more to IITs, NITs, IISERs, CSIR Labs or other Indian Government organizations or abroad in the last 10 years, PO copies or installation certificates along with model number and contact details of end user need to be submitted as the proof of supply. IIT Madras reserves its right to verify the claims submitted by the bidder and the feedback from the previous customers will be part of technical evaluation.

	III. Technical Specification for Table Top Sputter Coater
Sl.No.	Sub-components description
1	Vacuum chamber design:
	• Fully RF shielded, high grade stainless steel, SS304, electro-polished, non-magnetic, vertical cylindrical vacuum chamber should be less than 10 ltr capacity, having top lid opening with
	Viton 'O' ring, hinge-support and a suitable view port fitted with chamber to monitor processing.
	• Additional 5 numbers of glasses for viewport should be provided.
	• A vacuum port for turbo-molecular pump at the backside of chamber with automatic valve operation.
	• To prevent deposition on chamber wall, a removable type thin sheet liner must be provided.
	• Base plate should have support for connecting minimum 3 no's of magnetron sources arranged in either co-planar or confocal arrangement; gas inlet port, power feed through ports, source shutter on top of three targets.
	 Top plate should have appropriate ports/feed through for substrate holder with rotation,
	• Top plate should have appropriate ports/reed through for substrate holder with foration, heater, thermocouple etc.
	• The entire fabrication must adhere to international Vacuum Welding Standards,
	electrochemically polished chamber inner surface for low out gassing rate. All the
	components, sub-assemblies and final unit must be leak tested using Helium Mass
	Spectrometer Leak Detector to an individual leak rate of 3x10 ⁻⁹ mbar ltrs/sec.
2	System dimensions and support structure:
	• System should be cleanroom compatible (ISO-5 class 100, cleanroom compatible), tabletop, portable sputter tool.
	• Low-foot print area less than 60 cm x 90 cm with powder coated rack to place power supplies, other electrical systems.
3	Substrate holder with rotation and Z-shift:
Ū	• Substrate holder (SS-304) to position 6 to 8 nos. of 20 x 20 mm (holder 1) and 2 - 3 nos. of
	microscopic slides (holder 2). Two numbers of each type of substrate holder design.
	 The substrate holder capable to handle 4"wafer with rotation fixed at the center of top plate with variable speed (1–20 rpm).
	• Target to substrate distance should be variable ~ from 40 to 100 mm (z-shift)

1

· ·	
4	Substrate heating:
	• Should have variable substrate temperature option from 25 °C to 500 °C, stable temperature
	with accuracy of ± 1 °C, and suitable thermocouple with Digital PID Controller.
	• Temperature on the substrate should be able to control to up to 500 °C during sputter
	deposition process.
	• All necessary support documents on precision and control of temperature on the substrate
_	must be included in the technical bid.
5	Magnetron sources:
	• Minimum 2 numbers of reputed make, indirect water-cooled, RF/DC compatible, circular
	Magnetron Sources of 2 inch size, mounted on the base plate, sputter-up, co-planar arrangement capable to sputter from the target thickness of 6-8 mm.
	• Two sets of additional covers (both target clamp ring and outer shield of cathode) for each magnetron should be provided.
	 Shutter assembly to fully cover 4 inch substrate, during pre-sputtering.
	 Magnetrons should have capability for a long deposition run at a given process pressure
	under a constant power over a defined time and guarantee a uniformity figure of 300 nm Al
	at 0.5 Å/s, Ar gas at a process pressure of 1.5 mbar, 2" wafer, within \pm 2% non-uniformity.
	All support data must be included in the technical bid as well as should be demonstrated at
	the installation site.
6	RF and DC Power supplies:
	• 1 number of DC power supply, of reputed make, 500 W or above, having tight regulation
	≤ 0.2 %, variable ramp and 0.1% resolution with digital displays or interfaced with control
	panel.
	• 1 number of RF Power Generator of 150 W or above, of reputed make, nominal frequency of
	13.56 MHz with auto matching network load impedance of 50 Ω .
_	
7	Gas distribution system:
7	• A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter,
7	• A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs.
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber.
7 8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system:
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr.
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres,
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve.
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation.
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation.
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation.
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and
	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested.
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested.
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested. High resolution pressure control: Automatic pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements from a high-accuracy 0.1 m.bar full-scale capacitance
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested. High resolution pressure control: Automatic pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements from a high-accuracy 0.1 m.bar full-scale capacitance manometer.
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested. High resolution pressure control: Automatic pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements from a high-accuracy 0.1 m.bar full-scale capacitance manometer. All necessary support documents for high-resolution of ±0.1 m.bar pressure control during
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested. High resolution pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements from a high-accuracy 0.1 m.bar full-scale capacitance manometer.
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested. High resolution pressure control: Automatic pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements from a high-accuracy 0.1 m.bar full-scale capacitance manometer. All necessary support documents for high-resolution of ±0.1 m.bar pressure control during the deposition must be included in the technical bid. System software must automatically adjust MFC flow rates (including to a fixed, user-
8	 A Gas Manifold fabricated out of SS, 1 Nos. of reputed make MFC 2-80 sccm with filter, valves and inlet solenoid valve for Ar. Provision for 2 Nos. of MFCs. A solenoid operated isolation Valve for N₂ gas for venting the chamber. Vacuum pumping system: Reputed make dry scroll pump having displacement capacity of minimum 30 m³/hr. Forline trap with heater at the inlet, reputed make, water/air cooled turbo molecular pump having the pumping speed of at least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC Controlled high vacuum system with necessary valve. Vacuum pumping lines made out of SS-304 with bellow adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with controller taking its input the fast response capacitance manometer at suitable position to maintain quickly the required partial pressure of Argon inside the chamber to carry out the Sputtering operation. Base pressure: ultimate vacuum of at least <5 x 10⁻⁷ mbar within two hours of start of system, in clean, cold, empty degassed chamber after back filling the chamber with pure and dry Nitrogen. All the components, sub-assemblies and final unit must be leak tested. High resolution pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements from a high-accuracy 0.1 m.bar full-scale capacitance manometer.

r	
	• Upstream pressure control, which should be able to control the process pressure to ± 0.1
	m.bar from the set process pressure throughout the sputtering cycle and temperature ramps
1.0	for a minimum of 5 hrs.
10	Thin film deposition and quality:
	• High precision control on growth of thin film deposition using high-resolution pressure
	control from ~2 nm to few 100s of nm sputtering from single target or co-sputtering from
	two different targets.
	• Film should have uniformity within ± 2 atomic % variation in composition, ≤ 2 % variation in
	film thickness on edge-to-edge substrate size of above 20x20 mm.
	• Recipe for standard metals and semi-metal deposition.
	• Must have capability of low vacuum thin film deposition of minimum 1.5 m.bar for standard
	metals such as Al, Cu and Ti. Support data must be provided in the technical bid.
11	Auto/manual thin film deposition:
	• PLC based vacuum controller for complete automation of vacuum pumping with fully
	automatic and a provision for manual control. High resolution colour touchscreen HMI with
	purpose-designed easy-to-use, powerful software to enable deposition in either manual or
	automatic (i.e., per user-defined recipes) control modes. System control via industrial-grade,
	high-stability PLC electronics.
	• System should have USB and/or Ethernet connections for servicing/diagnostics and data
	logging/download during use from PC/laptop.
12	Safety interlocks:
	Water, low vacuum, high-vacuum, power supply connections and all necessary safety interlocks
	must be provided.
Terms	and Conditions
1.	Warranty:
	• Standard warranty for one year and extendable for two years.
	• On-site periodic checking/maintenance of the system after installation at least twice in a year
	during the warranty period.
	 Vendor shall commit to provide spares and support for 05 years after expiry of
	warranty period.
2.	Operating manual:
2.	Both electronic and hardcopy
	• The documentation/manual shall include all drawings, schematics, spares parts
2	catalogues and also sub-vendor's manuals.
3.	Installation/commission:
	• The system shall be installed / commissioned at customer site. The quotation shall be
	inclusive of all charges, if any, for installation and commissioning of the equipment by the
	vendor.
	• Extensive operation and maintenance training of at least three persons for one week at the
	customer site after the installation should be included.
	• Vendor to provide complete cleanroom compatible documentation/manuals soft copy/ hard
	copy for the systems.
	• The system shall conform to the Indian power supply standards, i.e. $230V \pm 5\%$, $50Hz$,
	Single Phase.
	• Warranty Certificates from manufacturer for bought out items like Power Supplies; Vacuum
	Pumps with Serial Numbers will have to be provided along with system documentation.
4.	Optional items:
-	-
1	Water Chiller unit
	 Water Chiller unit Quick venting accessories

TECHNICAL BID PROFORMA Tender No. ME/MSRO/147/2023/SPUTTERCOATR Item Name: Table Top Sputter Coater

1.0 Bidder Eligibility Criteria:

Ι	Bidder Eligibility Criteria-I (Public Procurement – Preference to Make in India)	Class I / Class II	Local Content value	Reference, Page No.
Ι	Only 'Class-I local suppliers' and 'Class-II local suppliers', as defined under DIPP, MoCI Order No. P-45021/2/2017-PP (BE II) dated 16 th September 2020 and other subsequent orders issued therein.			
2	EMD as per Tender or EMD is exempted for Micro and Small Enterprises (MSE) as defined in MSE Procurement Policy issued by Department of Micro, Small and Medium Enterprises (MSME) and Startups as recognized by Department of Industrial Policy & Promotion (DIPP). (MSE/MSME/DIPP PROOF should be enclosed in the cover containing technical bid).			

II Bidder Eligibility Criteria-II		Complied/Not Complied	Reference, Page No.
1	The participating Bidder's firm shall be the Original Equipment Manufacturer (OEM) or OEM Certified / authorized firm. (Annexure F)		
2	The bidder/OEM should have supplied at least 5 similar system or more to IITs, NITs, IISERs, CSIR Labs or other Indian Government organizations or abroad in the last 10 years, PO copies or installation certificates along with model number and contact details of end user need to be submitted as the proof of supply. IIT Madras reserves its right to verify the claims submitted by the bidder and the feedback from the previous customers will be part of technical evaluation.		

3.0Technical Compliance:

Sl.No.	Sub-components description		
1	Vacuum chamber design:		
	• Fully RF shielded, high grade stainless steel, SS304, electro-		
	polished, non-magnetic, vertical cylindrical vacuum chamber		
	should be less than 10 ltr capacity, having top lid opening with		
	Viton 'O' ring, hinge-support and a suitable view port fitted		
	with chamber to monitor processing.		
	• Additional 5 numbers of glasses for viewport should be		
	provided.		
	• A vacuum port for turbo-molecular pump at the backside of		
	chamber with automatic valve operation.		
	• To prevent deposition on chamber wall, a removable type thin		
	sheet liner must be provided.		
	• Base plate should have support for connecting minimum 3		
	no's of magnetron sources arranged in either co-planar or		
	confocal arrangement; gas inlet port, power feed through		
	ports, source shutter on top of three targets.		
	• Top plate should have appropriate ports/feed through for		
	substrate holder with rotation, heater, thermocouple etc.		
	• The entire fabrication must adhere to international Vacuum		

	Walding Oranda ale ale ale ale ale ale ale ale ale al	
	Welding Standards, electrochemically polished char	
	surface for low out gassing rate. All the compon assemblies and final unit must be leak tested usin	
	Mass Spectrometer Leak Detector to an individual le	
	3×10^{-9} mbar ltrs/sec.	
2	System dimensions and support structure:	
	• System should be cleanroom compatible (ISO-5	class 100,
	cleanroom compatible), tabletop, portable sputter too	
	• Low-foot print area less than 60 cm x 90 cm with	
	coated rack to place power supplies, other electrical s	<u> </u>
3	Substrate holder with rotation and Z-shift:	
	• Substrate holder (SS-304) to position 6 to 8 nos. of	of 20 x 20
	mm (holder 1) and 2 - 3 nos. of microscopic slides	
	Two numbers of each type of substrate holder design	1.
	• The substrate holder capable to handle 4"wafer with	
	fixed at the center of top plate with variable speed (1	
	• Target to substrate distance should be variable ~ f	rom 40 to
	100 mm (z-shift)	
4	Substrate heating:	
	• Should have variable substrate temperature option fr	
	to 500 °C, stable temperature with accuracy of \pm	1°C, and
	 suitable thermocouple with Digital PID Controller. Temperature on the substrate should be able to contr 	al to ye to
	• Temperature on the substrate should be able to contr 500 °C during sputter deposition process.	
		control of
	 All necessary support documents on precision and temperature on the substrate must be included in the 	
	bid.	
5	Magnetron sources:	
_	• Minimum 2 numbers of reputed make, indirect wat	ter-cooled.
	RF/DC compatible, circular Magnetron Sources of 2	
	mounted on the base plate, sputter-up, co-planar and	
	capable to sputter from the target thickness of 6-8 m	m
	• Shutter assembly to fully shield the substrate from th	e source.
	Cross contamination shields for isolation of each mag	gnetron.
	• Capability to perform co-sputtering deposition bet	tween any
	two magnetrons.	
	• Two sets of additional covers (both target clamp ring	
	shield of cathode) for each magnetron should be pro-	vided.
	• Shutter assembly to fully cover 4 inch substrate, d	uring pre-
	sputtering.	
	• Magnetrons should have capability for a long deposi	tion run at
	a given process pressure under a constant power	
	defined time and guarantee a uniformity figure of 3	
	at 0.5 Å/s, Ar gas at a process pressure of 1.5	
	wafer, within $\pm 2\%$ non-uniformity. All support dat	
	included in the technical bid as well as s	hould be
6	demonstrated at the installation site.	
6	RF and DC Power supplies:1 number of DC power supply, of reputed make,	500 W or
	• I number of DC power supply, of reputed make, above, having tight regulation ≤ 0.2 %, variable	
	0.1% resolution with digital displays or interfa	
	control panel.	
	• 1 number of RF Power Generator of 150 W or	above, of
	reputed make, nominal frequency of 13.56 MHz	

	matching network load impedance of 50 Ω .	
7	Gas distribution system:	
	• A Gas Manifold fabricated out of SS, 1 Nos. of reputed make	
	MFC 2-80 sccm with filter, valves and inlet solenoid valve for	
	Ar. Provision for 2 Nos. of MFCs.	
	• A solenoid operated isolation Valve for N ₂ gas for venting the	
	chamber.	
8	Vacuum pumping system:	
	• Reputed make dry scroll pump having displacement capacity	
	of minimum 30 m ³ /hr.	
	• Forline trap with heater at the inlet, reputed make, water/air	
	cooled turbo molecular pump having the pumping speed of at	
	least 85 ltrs/sec or above for a chamber volume of ~10 litres, vent valve and connecting cables, a fully automated PLC	
	Controlled high vacuum system with necessary valve.	
	• Vacuum pumping lines made out of SS-304 with bellow	
	adaptors, reputed make one wide range suitable gauge or Microvac Gauge, motorized throttle valve of suitable size with	
	controller taking its input the fast response capacitance	
	manometer at suitable position to maintain quickly the	
	required partial pressure of Argon inside the chamber to carry	
	out the Sputtering operation.	
	• Base pressure: ultimate vacuum of at least $<5 \times 10^{-7}$ mbar	
	within two hours of start of system, in clean, cold, empty	
	degassed chamber after back filling the chamber with pure	
	and dry Nitrogen.	
	• All the components, sub-assemblies and final unit must be	
	leak tested.	
9	High resolution pressure control:	
	• Automatic pressure control via PID feedback loop operated in response to high-resolution chamber pressure measurements	
	from a high-accuracy 0.1 m.bar full-scale capacitance	
	manometer.	
	• All necessary support documents for high-resolution of ±0.1	
	m.bar pressure control during the deposition must be included	
	in the technical bid.	
	• System software must automatically adjust MFC flow rates	
	(including to a fixed, user-defined ratio, if more than one	
	MFC is being operated simultaneously) to achieve the desired	
	chamber pressure. Pressure control resolution to 0.1 m.bar.	
	• Upstream pressure control, which should be able to control the	
	process pressure to ± 0.1 m.bar from the set process pressure	
	throughout the sputtering cycle and temperature ramps for a	
10	minimum of 5 hrs.	
10	Thin film deposition and quality:	
	• High precision control on growth of thin film deposition using high-resolution pressure control from ~2 nm to few 100s of	
	nm sputtering from single target or co-sputtering from two	
	different targets.	
	 Film should have uniformity within ±2 atomic % variation in 	
	• Finn should have uniformity within ± 2 atomic % variation in composition, ≤ 2 % variation in film thickness on edge-to-edge	
	substrate size of above $20x20$ mm.	
	Recipe for standard metals and semi-metal deposition.	
	1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1	

[
	• Must have capability of low vacuum thin film deposition of	
	minimum 1.5 m.bar for standard metals such as Al, Cu and Ti.	
	Support data must be provided in the technical bid.	
11	Auto/manual thin film deposition:	
	• PLC based vacuum controller for complete automation of	
	vacuum pumping with fully automatic and a provision for	
	manual control. High resolution colour touchscreen HMI with	
	purpose-designed easy-to-use, powerful software to enable	
	deposition in either manual or automatic (i.e., per user-defined	
	recipes) control modes. System control via industrial-grade,	
	high-stability PLC electronics.	
	• System should have USB and/or Ethernet connections for	
	servicing/diagnostics and data logging/download during use	
	from PC/laptop.	
12	Safety interlocks:	
	Water, low vacuum, high-vacuum, power supply connections and all	
	necessary safety interlocks must be provided.	
T		
	and Conditions	
5.	Warranty:	
	• Standard warranty for one year and extendable for two years.	
	• On-site periodic checking/maintenance of the system after	
	installation at least twice in a year during the warranty period.	
	• Vendor shall commit to provide spares and support for 05	
	years after expiry of warranty period.	
6.	Operating manual:	
	Both electronic and hardcopy	
	• The documentation/manual shall include all drawings,	
	schematics, spares parts catalogues and also sub-vendor's	
	manuals.	
7.	Installation/commission:	
	• The system shall be installed / commissioned at customer site.	
	The quotation shall be inclusive of all charges, if any, for	
	installation and commissioning of the equipment by the	
	vendor.	
	• Extensive operation and maintenance training of at least three	
	persons for one week at the customer site after the installation	
	should be included.	
	Vendor to provide complete cleanroom compatible	
	documentation/manuals soft copy/ hard copy for the systems.	
	• The system shall conform to the Indian power supply	
	standards, i.e. $230V \pm 5\%$, 50Hz, Single Phase	
	Warranty Certificates from manufacturer for bought out items	
	like Power Supplies; Vacuum Pumps with Serial Numbers	
	will have to be provided along with system documentation.	
8.	Optional items:	
	Water Chiller unit	
	Quick venting accessories	
<u> </u>		

SIGNATURE OF BIDDER ALONG WITH SEAL OF THE COMPANY WITH DATE

FINANCIAL BID (PROFORMA) - BILL OF QUANTITIES (BOQ)

Item Name: Table Top Sputter Coater Tender No. ME/MSRO/147/2023/SPUTTERCOATR

It. No	Description of work	Quantity	Units	Basic Rate in INR	GST in Percentage	Total Amount with taxes in INR
1	Table Top Sputter Coater with minimum 3 years warranty	1	No.			
2	Optional items: Water Chiller unit and Quick venting accessories	1	No.			
	Grand Total					

Total Amount Rupees in words _____

*Note - The optional items will not be considered for price bid evaluation.

FORMAT FOR AFFIDAVIT OF SELF-CERTIFICATION UNDER PREFERENCE TO MAKE IN INDIA – PER ITEM

Tender Reference Number:

Name of the item / Service:

Date:	
I/We	S/o, D/o, W/o,
Resident of	

Hereby solemnly affirm and declare as under:

That I will agree to abide by the terms and conditions of the Public Procurement (Preference to Make in India) Policy vide GoI Order no. P-45021/2/2017-PP (B.E.-II) dated 15.06.2017 (subsequently revised vide orders dated 28.05.2018, 29.05.2019and 04.06.2020) MOCI order No. 45021/2/2017-PP (BE II) Dt.16th September 2020 & P- 45021/102/2019-BE-II-Part (1) (E-50310) Dt.4th March 2021 and any subsequent modifications/Amendments, if any and

That the local content for all inputs which constitute the said item/service/work has been verified by me and I am responsible for the correctness of the claims made therein.

	I/We[name of the supplier] hereby confirm in respect of quoted items
	thatLocal Content is equal to or more than 50% and come under "Class-I Local Supplier"
	category.
	I/We [name of the supplier] hereby confirm in respect of quoted items
	that Local Content is equal to 20% but less than 50% and come under "Class-II Local Supplier"
	category.
• Th	e details of the location (s) at which the local value addition is made and the proportionate value of l
	ntent in percentage

Address _____ ___

Percentage of Local content: _____%

Authorized signatory (To be duly authorized by the Board of Directors) <Insert Name, Designation and Contact No.>

[Note: In case of procurement for a value in excess of Rs. 10 Crores, the bidders shall provide this certificate from statutory auditor or cost auditor of the company (in the case of companies) or from a practicing cost accountant or practicing chartered accountant (in respect of suppliers other than companies) giving the percentage of local content.]

This letter should be on the letterhead of the quoting firm and should be signed by a competent authority. Nonsubmission of this will lead to Disqualification of bids.

<u>Annexure – E</u>

(To be given on the letter head of the bidder)

No._____

Dated: _____

CERTIFICATE

(Bidders from India)

I have read the clause regarding restrictions on procurement from a bidder of a country which shares a land border with India and hereby certify that I am not from such a country.

OR (whichever is applicable)

(Bidders from Country which shares a land border with India)

I have read the clause regarding restrictions on procurement from a bidder of a country which shares a land border with India and hereby certify that I from ______ (Name of Country) and has been registered with the Competent Authority. I also certify that I fulfil all the requirements in this regard and is eligible to be considered. (Copy/ evidence of valid registration by the Competent Authority is to be attached)

Place: Date: Signature of the Tenderer Name & Address of the Tenderer with Office Stamp

OEM CERTIFICATION FORM (In Original Letter Head of OEM)

We are Original Equipment Manufacturers (OEM) of		(Name	e of the
company) Ms		(Name of the v	endor) is one	e of our
Distributors/Dealers/Resellers/Partners	(tick	one)	for	the
		. and is particip	ating in the	above-
mentioned tender by offering our produc	t model		(Nam	e of the
product with model number).				

..... is authorized to bid, sell and provide service support warranty for our product as mentioned above.

Name and Signature of the authorized signatory of OEM along with seal of the company with Date



CENTRE FOR INDUSTRIAL CONSULTANCY & SPONSORED RESEARCH (IC&SR) INDIAN INSTITUTE OF TECHNOLOGY MADRAS CHENNAI 600 036



ELECTRONIC CLEARING SERVICE (Credit Clearing)/ REAL TIME GROSS SETTLEMENT (RTGS) FACILITY FOR RECEIVING PAYMENTS

A. Details of Account Holder

Name of the Institution	Indian Institute of Technology - Madras
Complete Contact Address	Industrial Consultancy and Sponsored Research Indian Institute of Technology-Madras, IIT- Madras Campus Post Office, Sardar Patel Road, Guindy, CHENNAI - 600 036
Permanent Account Number	
(PAN)*	AAAAI3615G
GST REGISTERATION NO.	33AAAAI3615G1Z6
Telephone No./ Fax No.	Tel - 044-2257 8356
E- mail ID of the FO/AO/REG/DIR	dricsr@iitm.ac.in
B. Bank Account Details:	

Institution Account Name (As per Bank	The Registrar, Indian Institute of
Record)	Technology - Madras
Account No.	2722101003872
IFSC CODE	CNRB0002722
SWIFT CODE	CNRBINBBIIT
Bank Name (in full)	Canara Bank
Branch Name	IIT-Madras Branch
Complete Branch Address	Canara Bank,
	IIT-Madras Branch,
	IIT- Madras Campus Post Office,
	Sardar Patel Road,
	Guindy, CHENNAI - 600 036
MICR No.	600015085
Account Type	Savings Account

Certified that the Institute's account is in an RTGS enabled branch. I hereby declare that the particulars given above are correct and complete,

Date:

0 Signature of the Competent Authority of the Institution with seal. उप कुलसचित (आई.सी एवं एस.आर.) DEPUTY REGISTRAR (IC& SR) आई.आर्ड टी. मदास, चेन्ने I.I.T. MADRAS, CHENNAI - 600 036.

Phone : +91 (0) 44 2257 8062 / 8061 / 8060 Fax : +91 (0) 44 2257 0545 / 2257 8366 email : deanicsr@iitm.ac.in website : http://www.iitm.ac.in

21/01